**New Application** 136086-1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Schaepkens et al.

Application No.: New Application

Filed: Herewith

REPLACEABLE PLATE EXPANDED THERMAL PLASMA APPARATUS

**AND METHOD** 

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached Form PTO-1449. One copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

No fee should be required. However, please credit or debit Deposit Account No. 500917 as needed to ensure consideration of the disclosed information. Two copies of this paper are attached.

Respectfully submitted,

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Alexandria, Virginia 2003

Form PTO-1449 US Dept. of Commerce (REV. 8-83) PATENT & TRADEMARK OFFICE				ATTY DOCKET .136086-1		APPLICATION NO.		
INFORMATION DISCLOSURE STATEMENT				APPLICANT Schaepkens et al.				
(Use several sheets if necessary)				FILING DATE		GROUP		
U.S. PATENT	DOCU	MENTS						
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB FILING DATE CLAS IF APPROPRI- S ATE		OPRI-
		2003/0072881	4/2003	Yang et al.				
		2002/0050323	5/2002	Moisan et al.				
		2001/0022295	9/2001	Hwang				
		6,426,125	7/2002	Yang et al.				
		6,397,776	6/2002	Yang et al.				
		6,365,016	4/2002	Iacovangelo et al.				
		6,213,049	4/2001	Yang				
		6,110,544	8/2000	Yang et al.			<del></del>	
<del></del>		4,871,580	10/89	Schram et al.			<u> </u>	
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)  van de Sanden et al., The expanding thermal arc plasma: the low-flow								
		regime, Plasma Sources Sci. Technol., 7, pp. 28-35 (1998)						
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